

<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>				Docket Number (Optional) <b>SC12592ZP</b>		Application Number <b>Unknown</b>	
				Applicant(s) <b>McNeill et al.</b>			
				Filing Date <b>July 8, 2003</b>		Group Art Unit <b>Unknown</b>	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
X	1	U.S. 5,487,305	01/30/1996	Ristic et al.	73	514.32	07/12/1994
X	2	U.S. 5,594,171	01/14/1997	Ishida et al.	73	514.32	10/25/1995
X	3	U.S. 5,806,365	09/15/1998	Zunino et al.	73	514.16	04/30/1996
X	4	U.S. 5,939,633	08/17/1999	Judy	73	514.32	06/18/1997
X	5	U.S. 6,148,670	11/21/2000	Judy	73	514.32	06/10/1999
X	6	U.S. 6,223,598	05/01/2001	Judy	73	514.32	06/18/1997
FOREIGN PATENT DOCUMENTS							
REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
X	1	J. Connelly, A. Kourepinis, T. Marinis, "MICROMECHANICAL SENSORS IN TACTICAL GN&C APPLICATIONS", The Charles Stark Draper Laboratory, Inc., Published by the American Institute of Aeronautics and Astronautics, Inc. (2000).					
X	2	Giorgio Fontana, "High Performance Electrostatic Sensors and Actuators for LISA Proof Mass Control", arXiv:physics/0111006, Vol. 4 (Jan. 25, 2002)					
EXAMINER				DATE CONSIDERED			
<i>John Chapman</i>				<i>7/29/04</i>			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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*EXAMINER INITIAL	OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>		
X	3	Huikai Xie, Gary K. Fedder, "Vertical Comb-Finger Capacitive Actuation and Sensing For CMOS MEMS", Sensors and Actuators A95, 212-221 (2001)	
X	4	C. Byl, D. W. Howard, S. D. Collins and R. L. Smith, "MICROMACHINED, MULTI-AXIS, ACCELEROMETER with LIQUID PROOF MASS", Dept of Electrical & Computer Engineering, University of California, Davis, California, Final Report 1998-99 for MICRO Project 98-145	
X	5	Harvey Weinberg, "Dual Axis, Low g, Fully Integrated Accelerometers", Analog Dialogue 33-1 (1999 Analog Devices)	
X	6	Michael Kraft, "Micromachined Inertial Sensors - Recent Developments at BSAC", pp. 1-37 (University of California - Berkeley) (presentation given at the New England American Vacuum Society Meeting in Burlington, MA, 15/06/1998)	
X	7	"Low Cost $\pm 2$ g/ $\pm 10$ g Dual Axis IMEMS® Accelerometers with Digital Output - ADXL202/ADXL210", Analog Devices, Inc. (C3037b-2, Rev. B, April, 1999).	
X	8	"Low-Cost 2 g Dual-Axis Accelerometer with Duty Cycle Output - ADXL202E*", Analog Devices, Inc. (C02064-2.5-10, rev. A, 2000).	
X	9	Gary Li and Ampere A. Tseng, "Low Stress Packaging of a Micromachined Accelerometer", IEEE TRANSACTIONS ON ELECTRONICS PACKAGING MANUFACTURING, VOL. 24, NO. 1 (JANUARY 2001).	
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